DEC-27-02 04:38PM FROM- MATTINGLY, STANGER & MALUR, P.C.

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T-098 P.001

F-305

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Date: December 27, 2002

FACSIMILE COVER LETTER

Facsimile Number: (703) 872-9318

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To: Examiner D. Lee

Group Art Unit 2876, USPTO

TECHNOLOGY CENTER 2800

DEC 2 7 2002

From:

Mr. Daniel J. Stanger

MATTINGLY, STANGER & MALUR, P.C.

Re:

USSN 09/774,723

Attorney Docket No.: H-961

CERTIFICATION OF FACSIMILE TRANSMISSION

I hereby certify that the following listed documents are being facsimile transmitted to the U.S. Patent and Trademark Office on the date shown below:

Transmittal Letter; PRELIMINARY AMENDMENT.

Daniel J. Stanger

Reg. No. 32,846

Total Number of Pages (including cover sheet): 13

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DEC-27-02

04:38PM

FROM- MATTINGLY, STANGER & MALUR, P.C.

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T-098 P.002/013 F-305

FORM PTO-1083

PATENT

Case Docket No. H-961

In RE application of

T. HIROSE et al

Serial No.: 09/774,723

Group Art Unit:

2876

Filed: February 1, 2001

Examiner: D. Lee

For: POLISHING PAD SURFACE CONDITION EVALUATION METHOD AND AN APPARATUS THEREOF AND A METHOD OF PRODUCING A

SEMICONDUCTOR DEVICE

Assistant Commissioner for Patents Washington, D.C. 20231

FAX RECEIVED

Sir:

DEC 2 7 2002

Transmitted herewith is an Amendment in the above-identified application.

TECHNOLOGY CENTER 2800

Small entity status of this application under 37 CFR 1.9 and 1.27 has been established by a verified statement previously submitted. A verified statement to establish small entity status under 37 CFR 1.9 and 1.27 is enclosed.

No additional fee is required.

The fee has been calculated as shown below:

(COL. 1)			(COL. 2)		(COL. 3)		
		Ciplins Remaining After Amendment		Hig Pro Pr	phost No. evidusty mid For	Pri	ixtra 620ut
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SMALL ENTITY				
Rate	Additional Foo	OR		
x 9	8			
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+ 140	\$			
Total	8	OR		

Rate	Additional Fee	
× 18	8	0
× 84	\$	0
+ 280	8	0
Total	8	0

If the entry in Col. 1 is loss than the ontry in Col. 2, write 'O' in Col. 3.

If the 'Highest Number Previously Paid For' IN THIS SPACE is less tran 20, write '20' in this space.

If the 'Highest Number Previously Paid For' IN THIS SPACE is less than 3, write '3' in this space.

The 'Highest Number Previously Paid For' (Total or Independent) is the highest number found from the equivalent box in Col. 1 of a prior Amendment or the number of claims originally filed.

	Please charge my Deposit Account No. 50-1417 in the amount of \$				
	A check in the amount of \$ is attached in payment of:				
х	The Commissioner is hereby authorized to charge payment of the following fees associated with this communication or credit any overpayment to Deposit Account No. 50-1417.				
	X Any filing fees under 37 CFR 1.16 for the presentation of extra claims.				
	X Any patent application processing fees under 37 CFR 1.17.				
	X Any Extension of Time fees that are necessary, which are hereby requested if necessary.				

MATTINGLY, STANGER & MALUR, P.C. 1800 Diagonal Rd., Suite 370 Alexandria, Virginia 22314 (703) 684-1120

Date: December 27, 2002

32.846 Registration No. Attorney for Applicant(s)

T-098 P.003/013 F-305

H-961

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

T. HIROSE et al

Serial No. 09/774,723

Group Art Unit: 2876

Filed: February 1, 2001

Examiner: D. Lee

For: POLISHING PAD SURFACE CONDITION EVALUATION METHOD AND AN

APPARATUS THEREOF AND A METHOD OF PRODUCING A

SEMICONDUCTOR DEVICE

PRELIMINARY AMENDMENT

Commissioner for Patents Washington, D.C. 20231

December 27, 2002

Sir:

Before examination on the merits, please amend the above application as set forth below.

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DEC 2 7 2002

IN THE CLAIMS

TECHNOLOGY CENTER 2800

Rewrite claims 3, 9-11, 14, 16 and 20-23 as follows:

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3. (Amended) A method for evaluating polishing pad surface conditions as described in claim 5, wherein removal of polishing fluid adhered to said polishing pad surface is performed by flowing gas onto said polishing pad surface.